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Applicant: Hongyong ZHANG et al.

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INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
SAH	5,075,259	12/24/91	Moran	—	—	—
SAH	3,783,049	01/01/74	Sandera	—	—	—
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SAH	5,244,819	09/14/93	Yue	—	—	—
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SAH	Fortuna et al., "In Situ Study of Ion Beam Induced Si Crystallization from a Silicide Interface", Applied Surface Science, Vol. 73, 1993, pp. 264-267
SAH	Lee et al., "Pd Induced Lateral Crystallization of Amorphous Si Thin Films", Appl. Phys. Lett., Vol. 66, No. 13, March 27, 1995, pp. 1671-1673
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SAH	Liu et al., "Selective Area Crystallization of Amorphous Silicon Films by Low-Temperature Rapid Thermal Annealing", Appl. Phys. Lett., Vol. 55, No. 7, August 14, 1989, pp. 660-662
SAH	Caune et al., "Combined CW Laser and Furnace Annealing of Amorphous Si and Ge in Contact with Some Metals", Applied Surface Science, Vol. 36, 1989, pp. 567-604

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Date Considered

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